



Attorney's Docket No. 42P10606

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Qing Ma, Peng Cheng

Serial No. 09/894,334

Filed: June 27, 2001

For: SACRIFICIAL LAYER TECHNIQUE  
TO MAKE GAPS IN MEMS  
APPLICATIONS

Examiner: Coleman, William D.

Art Unit: 2823

Confirmation No.: 6477

**AMENDMENT AND RESPONSE TO OFFICE ACTION**

Mail Stop Non-Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed June 11, 2003, please amend the above-identified application as follows.